

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:	Wayne G. RENKEN		
Title:	Process Condition Sensing Wafer and Data Analysis System		
Application No.:	10/685,550	Filing Date:	October 14, 2003
Examiner:	Hezron WILLIAMS	Group Art Unit:	2856
Docket No.:	SENS.005US1	Conf. No.:	4924

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT ACCOMPANYING RCE

Sir:

This is in response to the final Office Action dated March 16, 2006, setting a period for response expiring on June 16, 2006. An appropriate request for extension of time accompanies this paper.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Amendments to the Drawings are not being made.

Remarks begin on page 8 of this paper.